

## **NNCI 2018 Etch Symposium-October 11<sup>th</sup> at Stanford University**

As part of the NNCI (National Nanotechnology Coordinated Infrastructure, supported by NSF, the National Science Foundation) Etch Workshop, a day long symposium will be held on October 11<sup>th</sup> 2018 at Stanford University. Symposium will feature invited talks by etch equipment manufacturers as well as contributed talks from NNCI technical staff and Exhibits. This symposium is open to researchers from academics and industry in addition to the NNCI member institutions.

Exhibits from NNCI affiliates and equipment vendors and other service providers will be open throughout the day for distribution of material and discussions with representatives. Participating vendors to date are: Applied Materials, Lam Research, Plasma-Therm, Ulvac, Allwin 21, SPTS, Oxford, Memsstar, Samco, Qualtx and Nanosilicon. We would like to acknowledge the sponsorship support from these suppliers.

### **Agenda: Location – Paul G. Allen Building; Room 101X**

#### **Contributed Talks From Faculty Researchers, NNCI Researchers and Vendor Experts:**

- 8:00-8:30am: Breakfast
- 8:30-8:40am: Welcome - Professor Nicholas Melosh, Stanford University
- 8:40-9:10am: Joydeep Guha-Applied Materials-"Semiconductor Scaling in the Era of Data Explosion"
- 9:10-9:40am: Haig Atikian-Harvard-"Directional Diamond Etching"
- 9:40-10:10am: David Lishan-Plasma-Therm-"Plasma Dicing and F.A.S.T. CVD"
- 10:10-10:30am: Break/Vendor Exhibit
- 10:30-11:00: Keren Kanarik-Lam Research-"Atomic Layer Etching-Rethinking the Art of the Etch"
- 11:00-11:30: Ling Xie-Harvard-"Crystallographic Orientation Dependent RIE"
- 11:30-12:00: Samco-"ICP Etching of Compound Semiconductors-GaAs, InP, and GaN devices"
- Noon-1:30pm: Lunch and Vendor Exhibits
- 1:30-2:00pm: Steve Vargo-SPTS- "Deep oxide etching"
- 2:00-2:30pm: Jim McVittie-Stanford-"Plasma Damage"
- 2:30-3:00pm: Demetrius Chrysostomou-Oxford Instruments-"Atomic Layer Etching"
- 3:00-3:30pm: Tony McKie-Memsstar-"Vapor Phase Etching of Sacrificial Materials-Maximizing Their Performance"
- 3:30-4:00pm: Break
- 4:00-4:30pm: wrap up, Q & A
- 4:30-5:30pm SNF & SNSF tours

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### **[Link to 2018 NNCI Etch Symposium Registration](#)**

If you have any questions regarding the event, please contact Usha Raghuram ([usha@stanford.edu](mailto:usha@stanford.edu)).